

# Modules of the 2025 course

Topics covered	No	Lecture/Date
VAT Photo polymerization (history) – DLP printer – light engine – part I	5	20.03.2025
DLP printer – chemical components in a photoresin – role of oxygen – CLIP method– part II	6	27.03.2025
Tomographic Volumetric Additive Manufacturing (TVAM): principles and applications	7	03.04.2025
Two photon Polymerization : nanoscale printing	8	10.04.2025
Two photon Polymerization : applications	9	17.04.2025
EASTER BREAK		22.04.2025
Prof. Paul Dalton, University of Oregon: Met Electro Writing (nanoscale)	10	1.05.2025
Gari Arutinov, Holst Center for AM: Mass transfer of microcomponents	11	08.05.2025
Julian Schneider: Scrona	12	15.05.2025
Patrizia Richner: Sonova (hearing aids). // <b>Design Competition</b>	13	22.05.2025

QUIZZ #2

Although the wavelength is 780nm,  
It is possible to make structures  
With size 65 nm !!

By adjusting the dose i.e  
*Intensity \* exposure times*

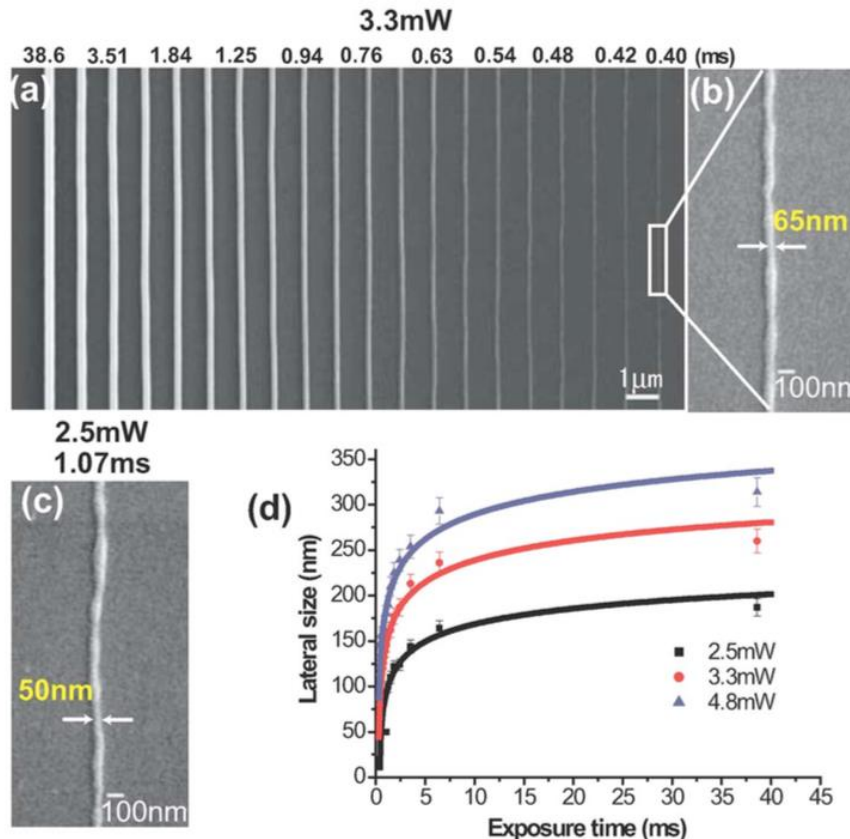
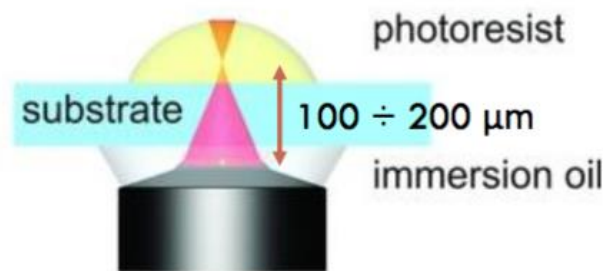
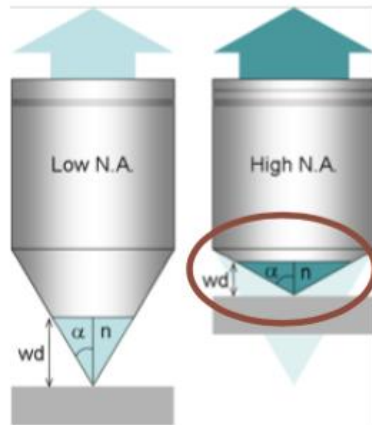


FIG. 2. (Color online) (a) SEM images of photocured polymer lines obtained using a laser power of 3.3 mW, after various exposure times. (b) Enlarged image of a line fabricated with a laser power of 3.3 mW and an exposure time of 0.4 ms. (c) A polymer line with a width of 50 nm. (d) LSR vs exposure time under different laser powers (lines are calculated results).

# Height Limitation of 3D structures



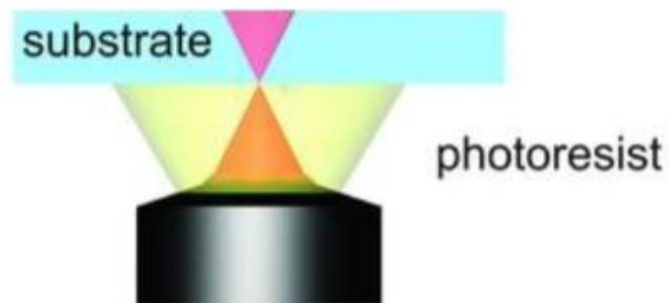
**E.G.:** Zeiss Objective Plan-Apochromat  
63x/1.40 Oil DIC

- $M=63\times$
- $NA=1.4$
- $WD=190\text{ }\mu\text{m}$

**Max height  $\sim 10\text{ }\mu\text{m}$**

DW: Working distance of the microscope objective i.e  
The distance between the objective and the focal distance

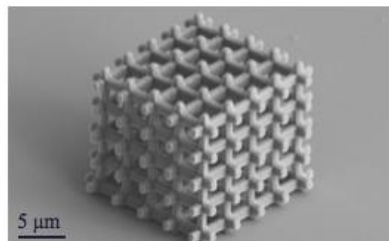
- DIP-IN



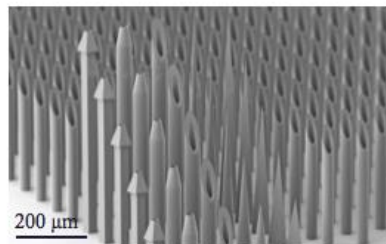
Only photoresists with matched  $n$   
can be used

# Dip-in mode

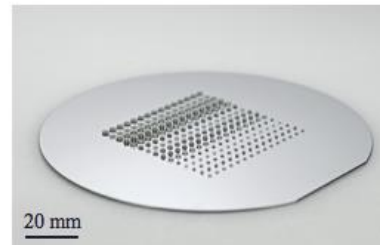
**Small feature**



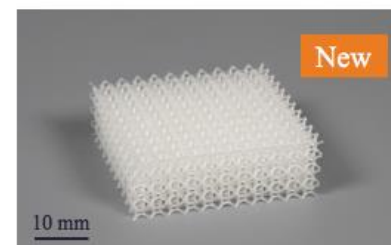
**Medium feature**



**Large features**



**Extra large feature**



Magnification  
NA

**63x**  
**1.4**

**25x**  
**0.8**

**10x**  
**0.3**

**5x**  
**0.16**

Calibrated print  
field diameter

**270 μm**

**700 μm**

**1,750 μm**

**3,200 μm**

Working  
distance

**360 μm**

**380 μm**

**2,600 μm**

**18,500 μm**

Scan speed  
(max.)

**100 mm/s**

**250 mm/s**

**625 mm/s**

**1,250 mm/s**

Slicing range  
(typical)

**0.1 – 0.8 μm**

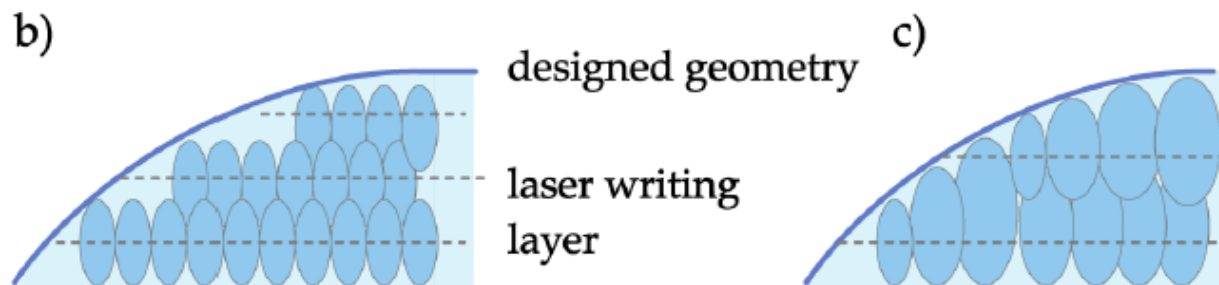
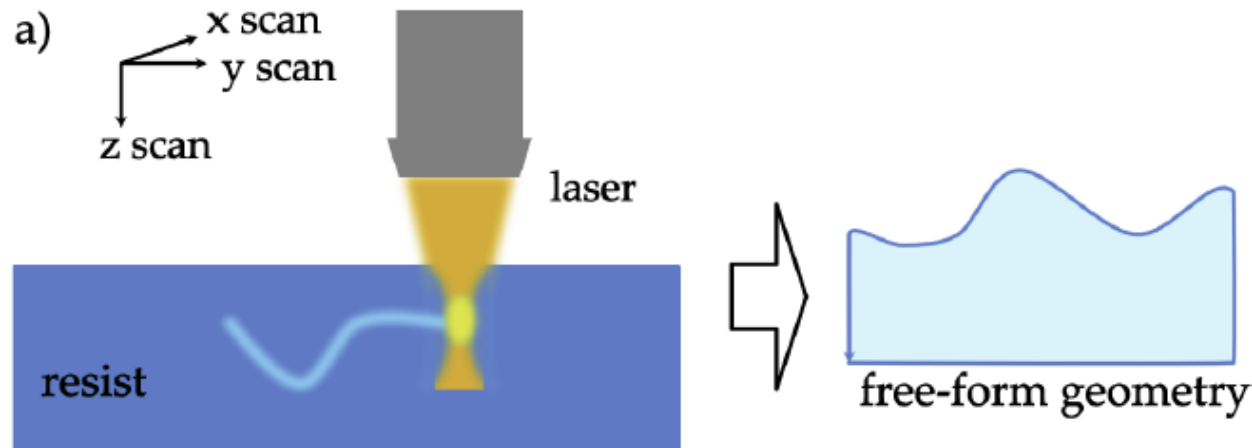
**0.5 – 3 μm**

**2 – 10 μm**

**5 – 100 μm**

# Two-photon polymerization (2PP)

## Two-photon grayscale lithography (2GL)



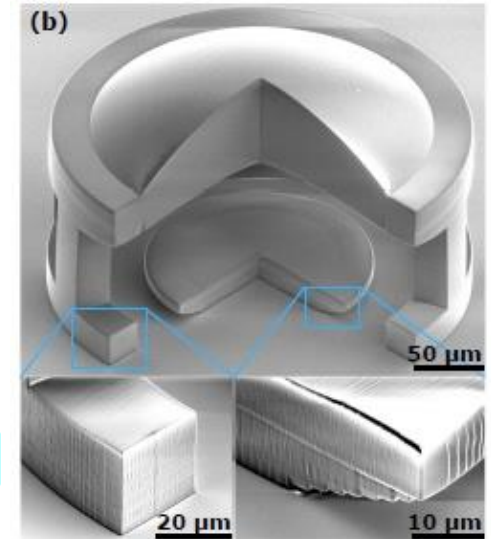
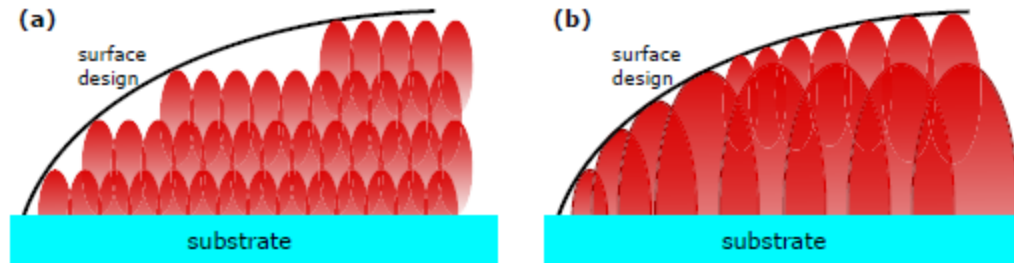


## Complex aspherical singlet and doublet microoptics by grayscale 3D printing

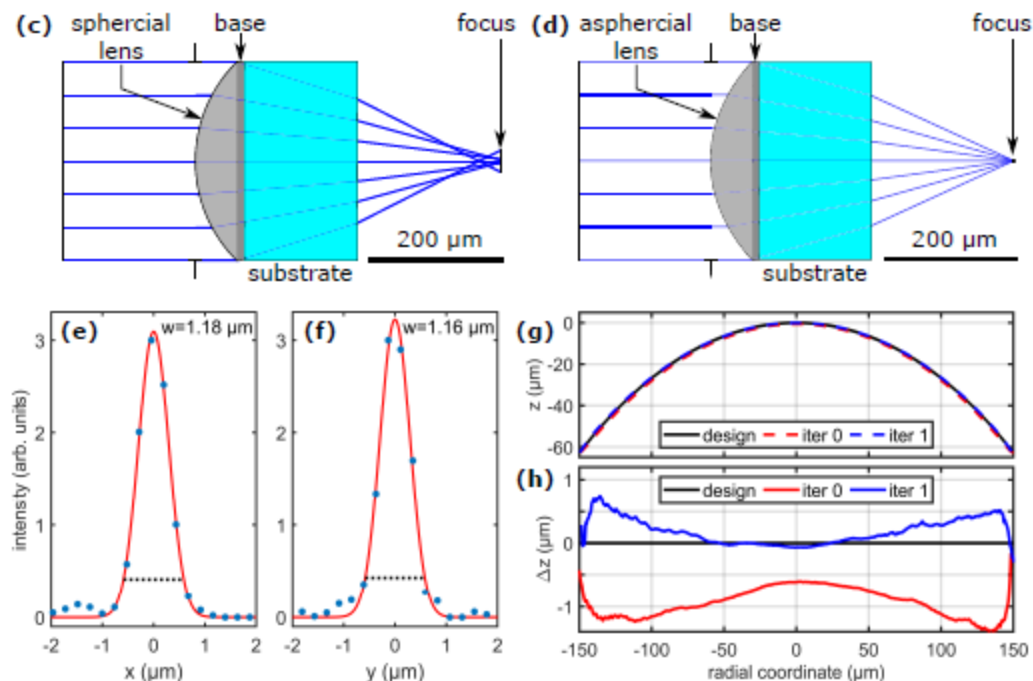
LEANDER SIEGLE,\*  SIMON RISTOK,  AND HARALD GIESSEN 

4th Physics Institute and Research Center SCoPE, University of Stuttgart, Pfaffenwaldring 57, 70569 Stuttgart, Germany

\*[l.siegle@pi4.uni-stuttgart.de](mailto:l.siegle@pi4.uni-stuttgart.de)

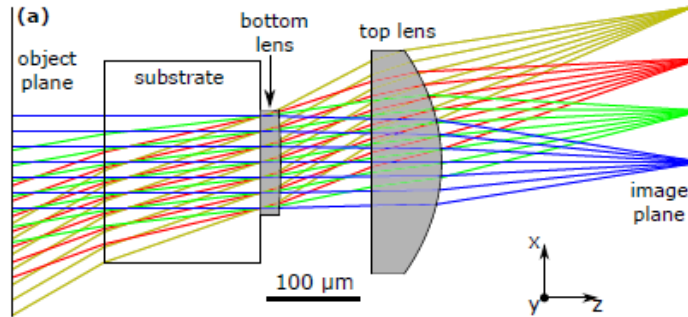


# 2GL on Aspherical Singlet and Doublet

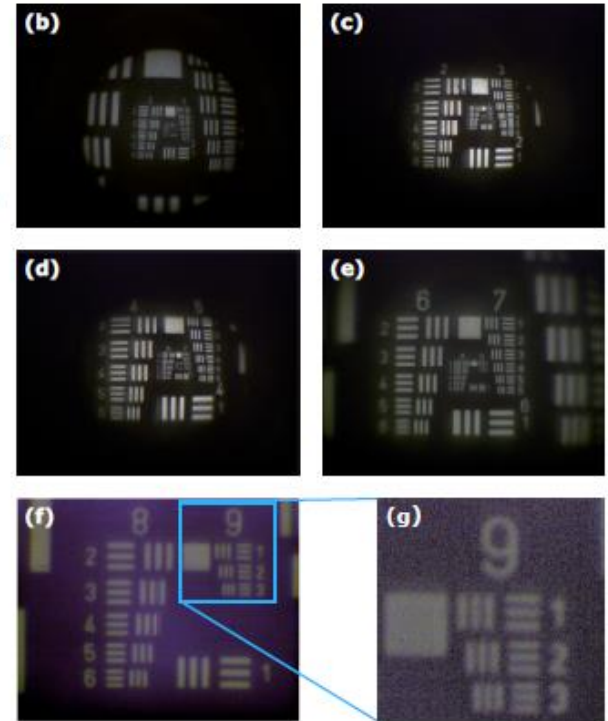
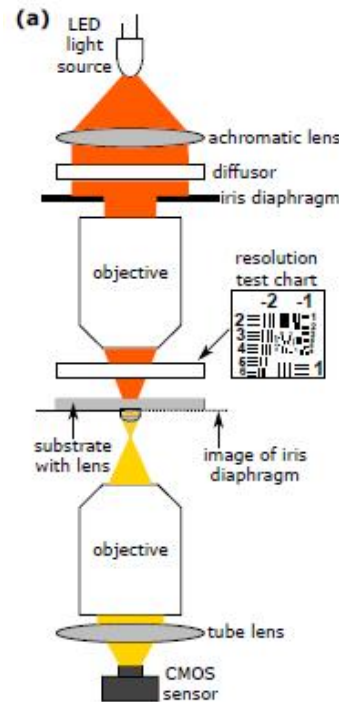




# 2GL on Aspherical Singlet and Doublet

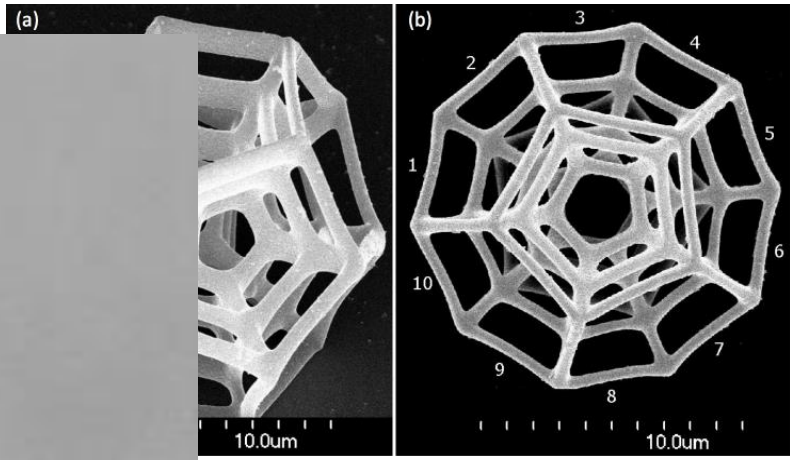
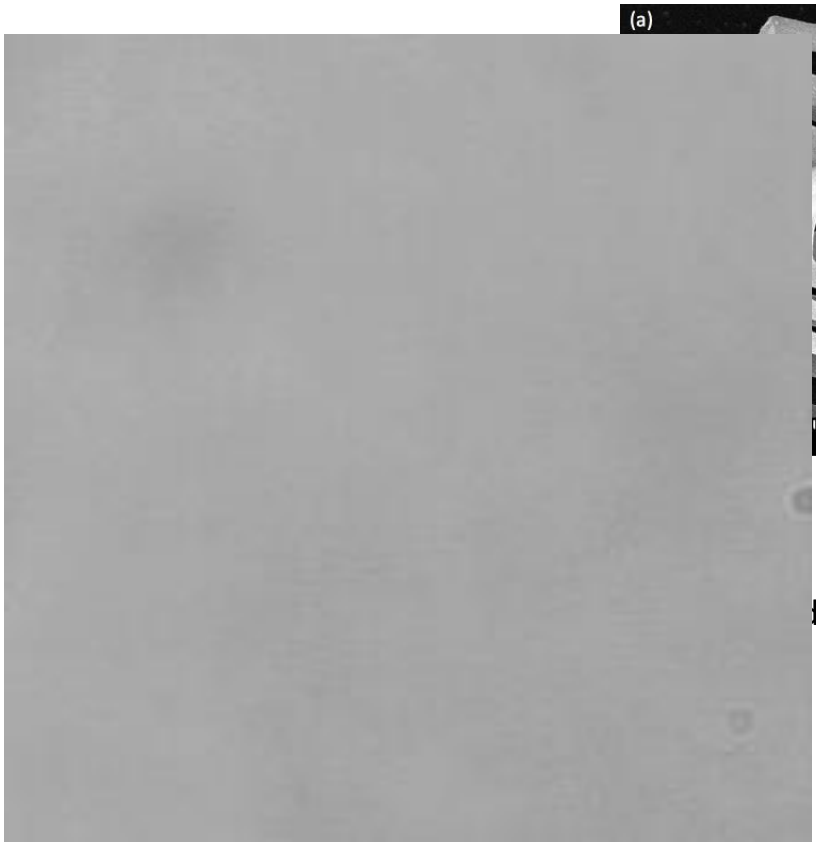
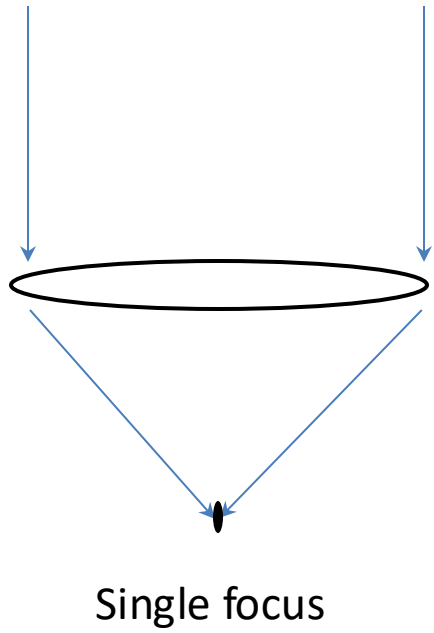


field of view of 60°  
deviations 20 nm for the bottom lens  
deviations 100 nm for the larger top lens  
resolution 645 lp/mm



# How to increase printing speed ?

Holographic multi-focus 3D two-photon polymerization with real-time calculated holograms – Optics Express 2014



Fabricated by 550 projections giving each 5 Foci.

This can be generated by  
DLP for example  
and Micro 425 Advanced Additive manufacturing technologies

# Example: bio-printing

5 ms exposure, 3 mW/foci → 200 Hz  
750 foci → 2.2 W



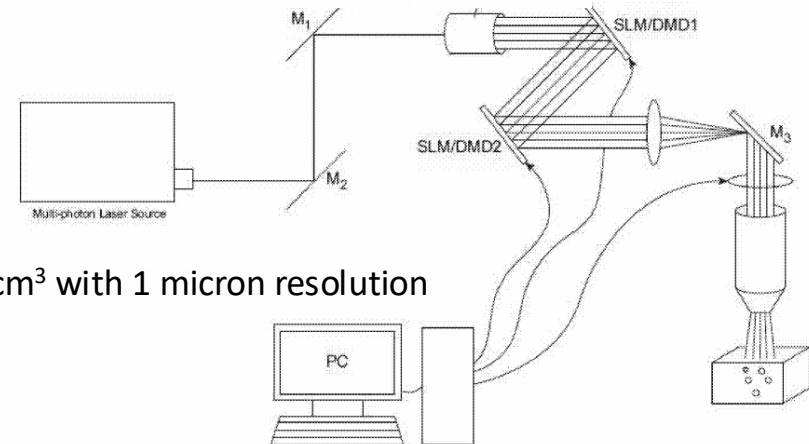
(19) **United States**  
(12) **Patent Application Publication**  
**MATHEU**

**EPFL**

(54) **METHODS AND SYSTEMS FOR PRINTING BIOLOGICAL MATERIAL**

(71) Applicant: **Prellis Biologics, Inc.**, San Francisco, CA (US)

(52)



Time to print 1 cm<sup>3</sup> with 1 micron resolution

$$fab\ time = f \cdot n_{voxels} / \#voxels/sec$$

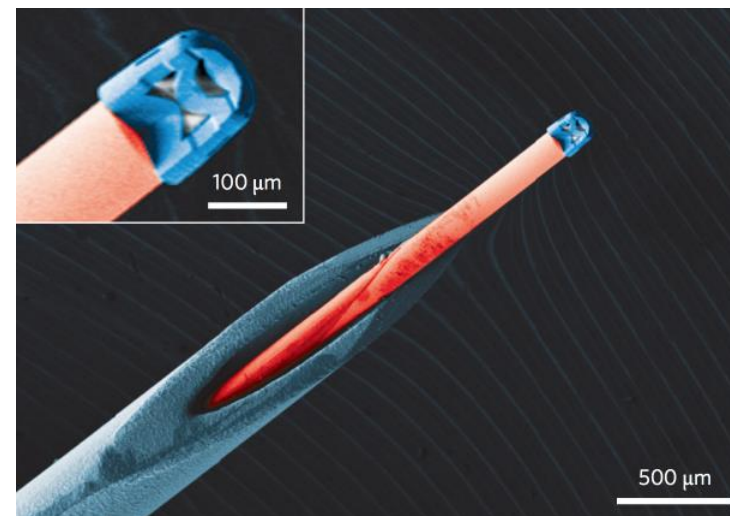
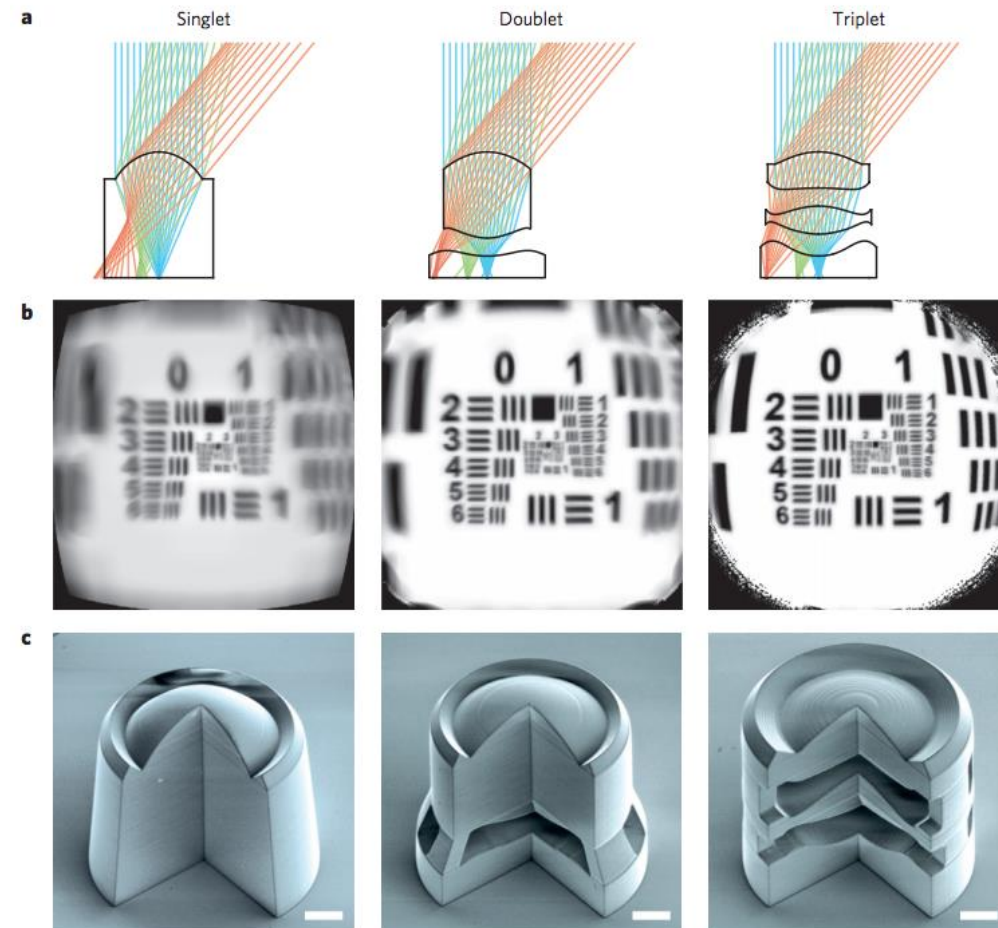
Fill factor 1%

15%

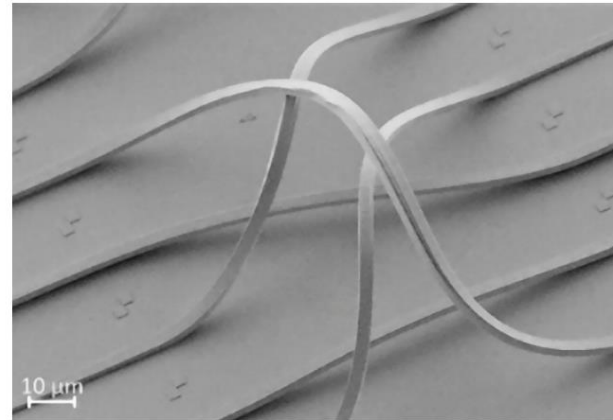
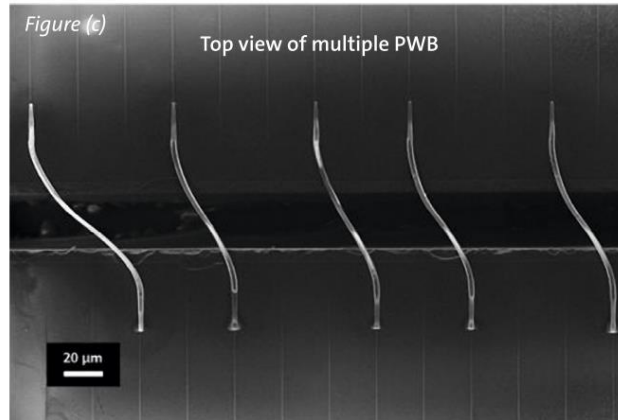
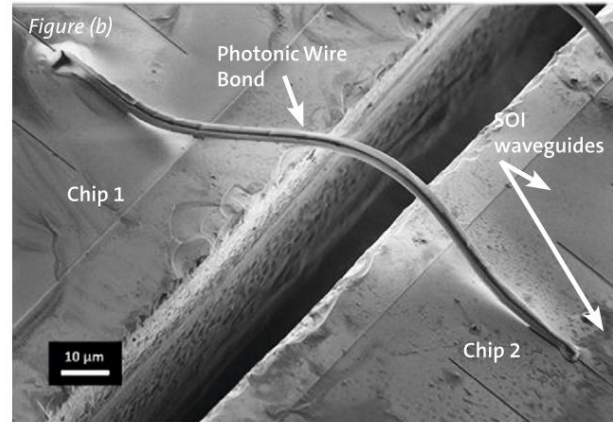
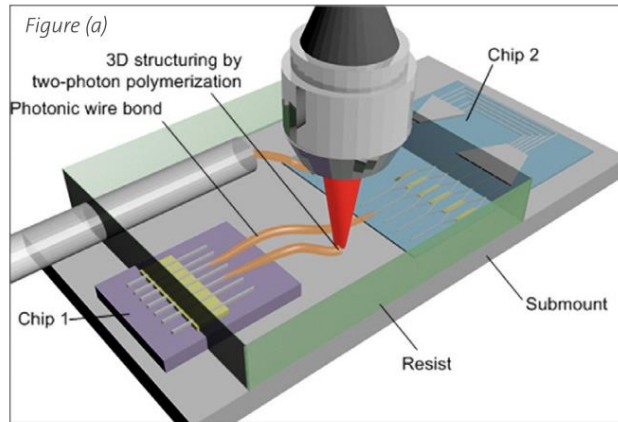
18.5 h

11.5 days

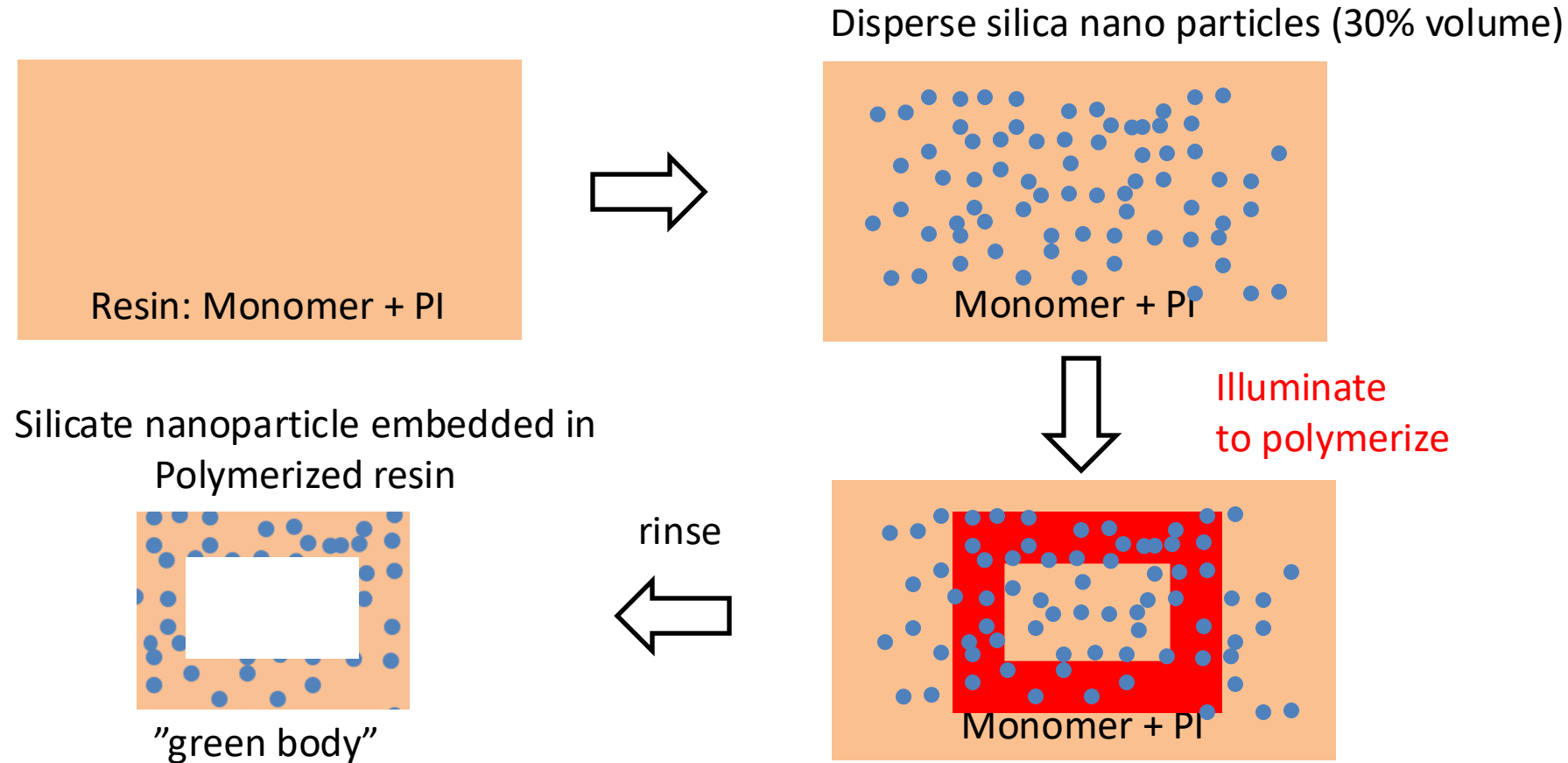
# Two-photon direct laser writing of ultracompact multi-lens objectives



Transparent polymer material

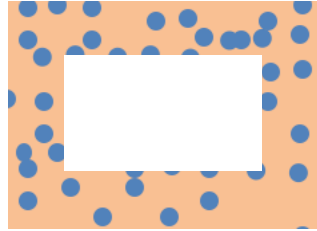


# 2 Photon Polymerization : glass



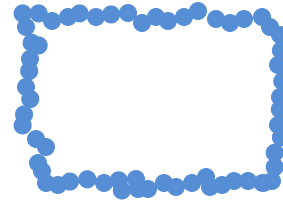
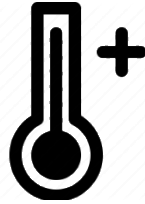


# 2 Photon Polymerization : glass



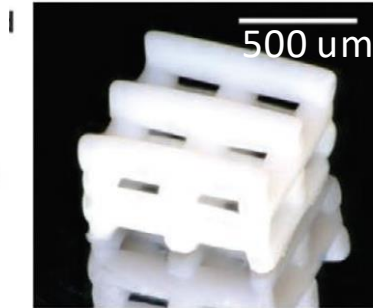
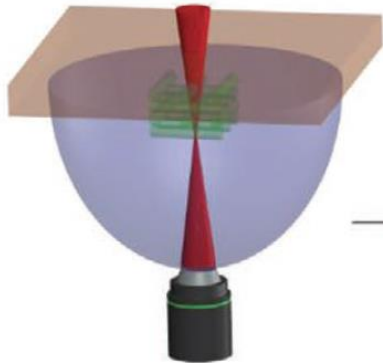
"green body"

oven  
→  
1300°C



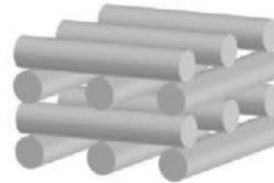
The silica particles sinter and the polymer are vaporized by the heat  
Leaving only the merged silicate particles

a



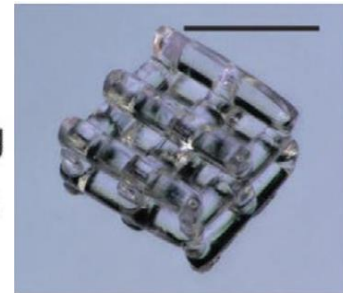
green part

binding  
→  
100 °C



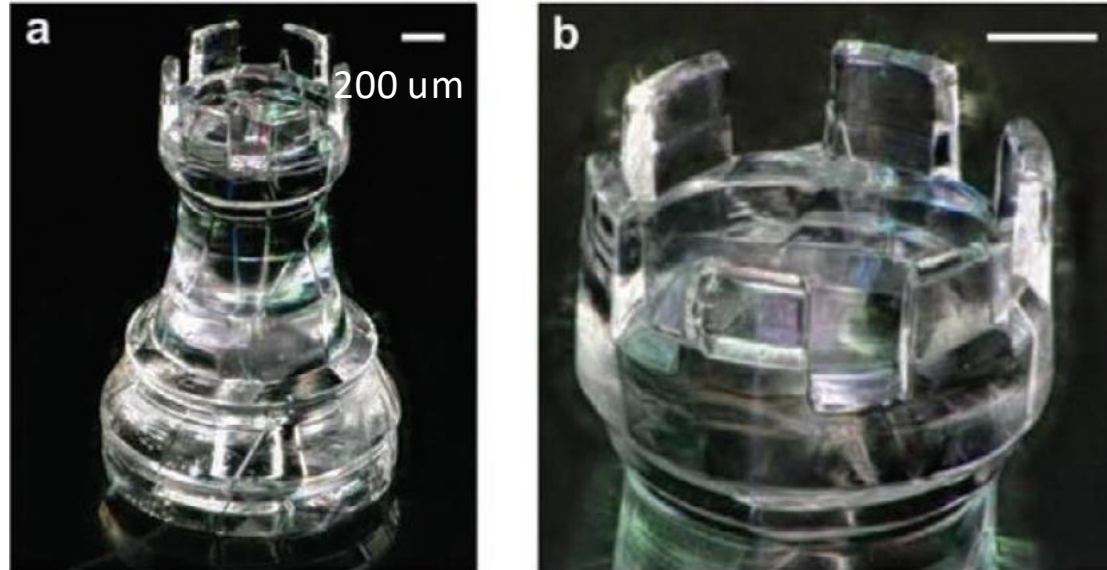
brown part

Sintering  
→  
1300 °C



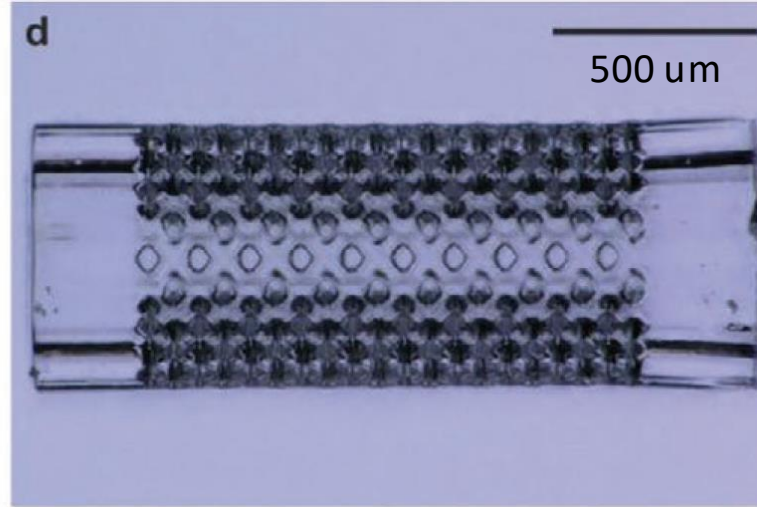
fused silica

Direct laser writing=2 Photon Polymerization



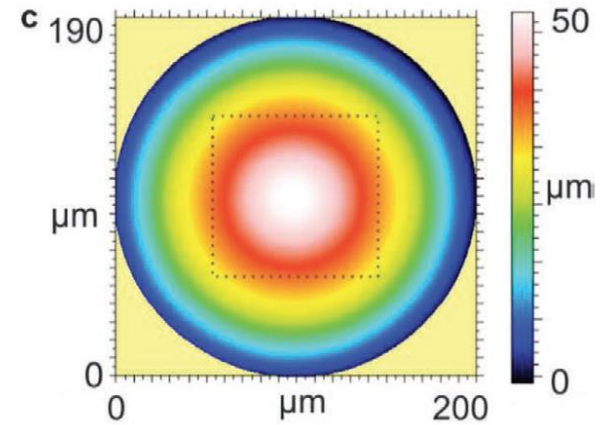
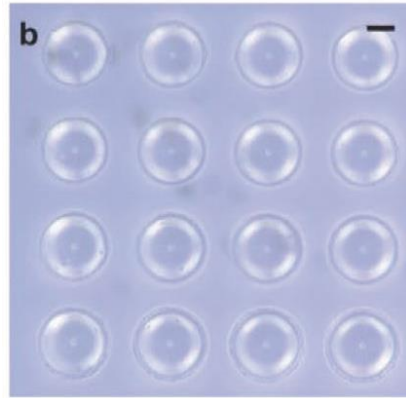
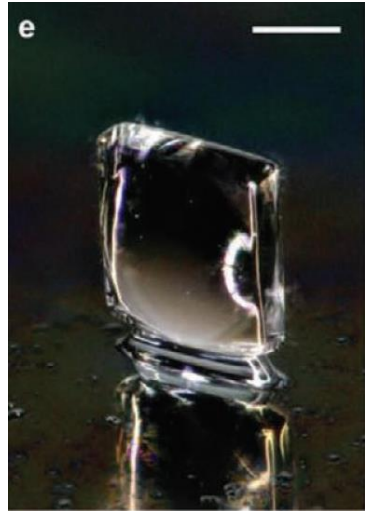
Slicing 5  $\mu\text{m}$ , hatching 1  $\mu\text{m}$ , scan speed 100  $\text{mms}^{-1}$





Micro filter element with 55 um holes

Slicing 5  $\mu\text{m}$ , hatching 1  $\mu\text{m}$ , scan speed 100  $\text{mms}^{-1}$



Glass micro lenses

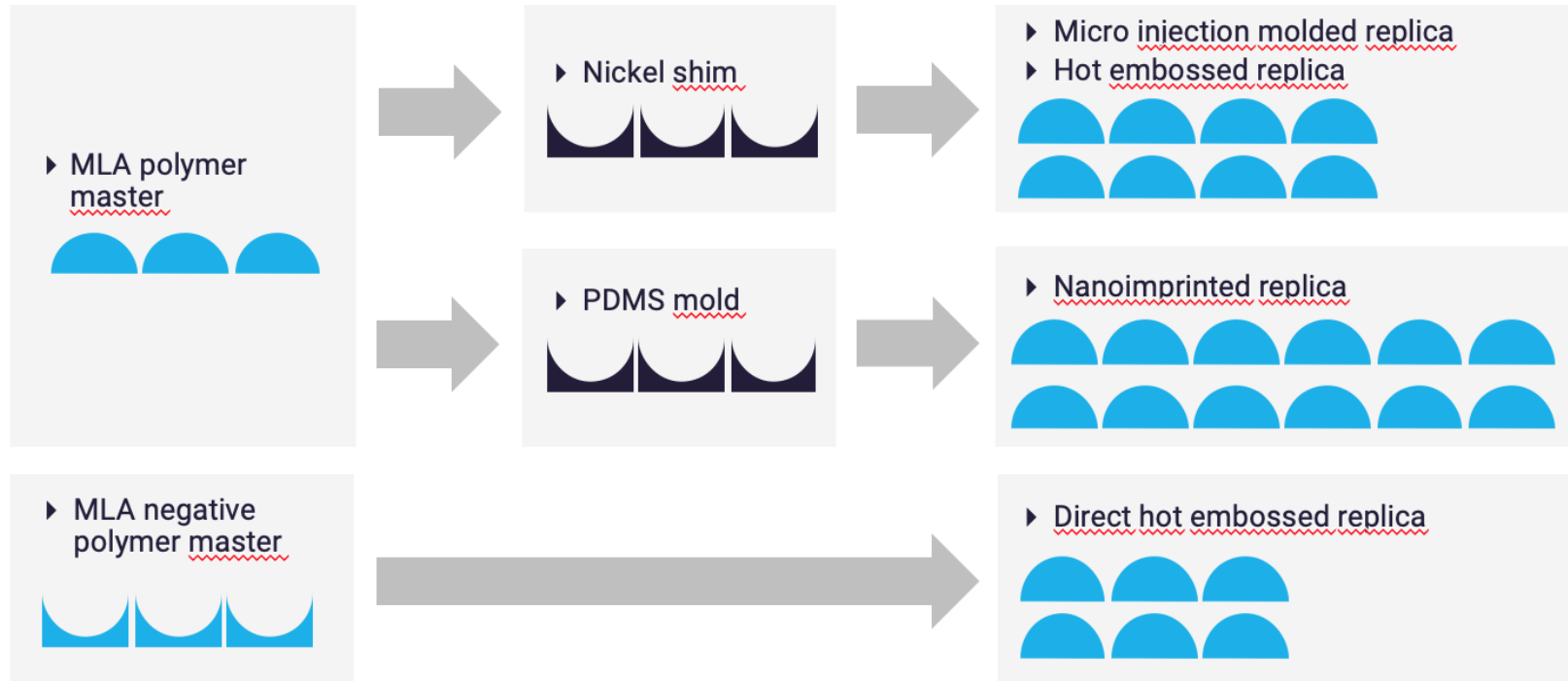
Surface roughness  $R_a \approx 6.1 \text{ nm}$

# High precision parts for replication



## Replication processes

### From polymer master to small series production



2-photon  
Printer  
By Nanoscribe

At Cmi  
BM building

